



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Sujit Sharan and Gurtej S. Sandhu

Serial No.: 09/825,612

Filed: April 3, 2001

For: METHOD FOR PECVD DEPOSITION OF SELECTED  
MATERIAL FILMS

§  
§ Group Art Unit: 2829  
§  
§ Examiner: Lisa Kilday  
§  
§ Atty. Docket: 95-07166  
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§

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RESPONSE TO THE OFFICE ACTION DATED SEPTEMBER 11, 2002

Commissioner for Patents

Washington, D.C. 20231

Dear Sir:

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Assistant Commissioner for Patents and Trademarks  
Washington, DC 20231  
on

Date 1/13/03

Susan Jerome  
Signature

Applicants herein respond to the Office Action dated September 11, 2002.

REMARKS

Claims 13-18, 22-26, and 28 are pending.

Claims 13-18, 22-26, and 28 are rejected.

Applicants request reconsideration of claims 13-18, 22-26, and 28.

The Examiner rejected claims 13-15, 22-26, and 28 under §102 as being anticipated by the matters expressed in Chang (U.S. Pat. No. 6,294,466). Applicants contend that the claims contain limitations that Chang fails to disclose. Independent claim 13, for example, requires a gas that functions as a chemically inert charged species producer. Claim 13 further requires an interaction